

10698726\_CLS  
Most Frequently Occurring Classifications of Patents Returned  
From A Search of 10698726 on June 16, 2004

Original Classifications

3	250/492.3
3	313/309
2	204/298.04
2	250/492.2
2	315/307
2	315/5.37
2	445/24

Cross-Reference Classifications

6	313/336
3	204/298.16
3	313/293
3	313/351
3	445/50
2	156/345.46
2	204/298.19
2	204/298.37
2	313/231.31
2	313/304
2	313/309
2	313/361.1
2	313/414
2	313/447
2	313/495
2	315/106
2	315/107
2	315/291

Combined Classifications

7	313/336
5	313/309
4	204/298.16
4	250/492.3
4	313/293
3	250/492.2
3	313/351
3	313/495
3	315/107
3	445/24
3	445/50
2	156/345.46
2	204/298.04
2	204/298.19

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2 204/298.37  
2 219/121.27  
2 250/423R  
2 313/231.31  
2 313/304  
2 313/310  
2 313/361.1  
2 313/414  
2 313/447  
2 315/106  
2 315/111.21  
2 315/291  
2 315/3.5  
2 315/307  
2 315/5.37  
2 378/113

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Titles of Most Frequently Occurring Classifications of Patents Returned

From A Search of 10698726 on June 16, 2004

- 7 313/336 (1 OR, 6 XR)
  - Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
  - 313/326 ELECTRODE AND SHIELD STRUCTURES
  - 313/336 .Point source cathodes
  
- 5 313/309 (3 OR, 2 XR)
  - Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
  - 313/309 DISCHARGE DEVICES HAVING A MULTIPOINTED OR SERRATED EDGE ELECTRODE
  
- 4 204/298.16 (1 OR, 3 XR)
  - Class 204 : CHEMISTRY: ELECTRICAL AND WAVE ENERGY
  - 204/193 APPARATUS
  - 204/298.01 .Coating, forming or etching by sputtering
  - 204/298.02 ..Coating
  - 204/298.16 ...Magnetically enhanced
  
- 4 250/492.3 (3 OR, 1 XR)
  - Class 250 : RADIANT ENERGY
  - 250/492.1 IRRADIATION OF OBJECTS OR MATERIAL
  - 250/492.3 .Ion or electron beam irradiation
  
- 4 313/293 (1 OR, 3 XR)
  - Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
  - 313/293 DISCHARGING DEVICES WITH APERTURED ELECTRODE (E.G., GRID) INTERPOSED BETWEEN TWO ELECTRODES
  
- 3 250/492.2 (2 OR, 1 XR)
  - Class 250 : RADIANT ENERGY
  - 250/492.1 IRRADIATION OF OBJECTS OR MATERIAL
  - 250/492.2 .Irradiation of semiconductor devices
  
- 3 313/351 (0 OR, 3 XR)
  - Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
  - 313/326 ELECTRODE AND SHIELD STRUCTURES
  - 313/351 .Multipointed or serrated edge electrode
  
- 3 313/495 (1 OR, 2 XR)
  - Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES
  - 313/483 WITH LUMINESCENT SOLID OR LIQUID MATERIAL
  - 313/495 .Vacuum-type tube

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- 3 315/107 (1 OR, 2 XR)  
 Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
 315/94 WITH CATHODE OR CATHODE HEATER SUPPLY CIRCUIT  
 315/107 .Automatic cut-out or voltage regulator in the  
 cathode or heater circuit
- 3 445/24 (2 OR, 1 XR)  
 Class 445 : ELECTRIC LAMP OR SPACE DISCHARGE COMPONENT OR  
 DEVICE MANUFACTURING  
 445/1 PROCESS  
 445/23 .With assembly or disassembly  
 445/24 ..Display or gas panel making
- 3 445/50 (0 OR, 3 XR)  
 Class 445 : ELECTRIC LAMP OR SPACE DISCHARGE COMPONENT OR  
 DEVICE MANUFACTURING  
 445/1 PROCESS  
 445/46 .Electrode making  
 445/49 ..Electrode shaping  
 445/50 ...Emissive type
- 2 156/345.46 (0 OR, 2 XR)  
 Class 156 : ADHESIVE BONDING AND MISCELLANEOUS CHEMICAL  
 MANUFACTURE  
 156/345.1 DIFFERENTIAL FLUID ETCHING APPARATUS  
 156/345.43 .Having glow discharge electrode gas energizin  
 g  
 means  
 156/345.46 ..With magnetic field generating means for  
 control of the etchant gas
- 2 204/298.04 (2 OR, 0 XR)  
 Class 204 : CHEMISTRY: ELECTRICAL AND WAVE ENERGY  
 204/193 APPARATUS  
 204/298.01 .Coating, forming or etching by sputtering  
 204/298.02 ..Coating  
 204/298.04 ...Ion beam sputter deposition
- 2 204/298.19 (0 OR, 2 XR)  
 Class 204 : CHEMISTRY: ELECTRICAL AND WAVE ENERGY  
 204/193 APPARATUS  
 204/298.01 .Coating, forming or etching by sputtering  
 204/298.02 ..Coating  
 204/298.16 ...Magnetically enhanced  
 204/298.17 ....Flux passes through target surface  
 204/298.19 .....Planar magnetron

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2 204/298.37 (0 OR, 2 XR)  
 Class 204 : CHEMISTRY: ELECTRICAL AND WAVE ENERGY  
 204/193 APPARATUS  
 204/298.01 .Coating, forming or etching by sputtering  
 204/298.31 ..Etching  
 204/298.37 ...Magnetically enhanced

2 219/121.27 (1 OR, 1 XR)  
 Class 219 : ELECTRIC HEATING  
 219/50 METAL HEATING (E.G., RESISTANCE HEATING)  
 219/121.11 .By arc  
 219/121.12 ..Using electron beam  
 219/121.25 ...Shaping  
 219/121.27 ....With electrode or gun structure

2 250/423R (1 OR, 1 XR)  
 Class 250 : RADIANT ENERGY  
 250/423R ION GENERATION

2 313/231.31 (0 OR, 2 XR)  
 Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
 313/231.01 FLUENT MATERIAL SUPPLY OR FLOW DIRECTING MEANS  
 313/231.31 .Plasma

2 313/304 (0 OR, 2 XR)  
 Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
 313/293 DISCHARGING DEVICES WITH APERTURED ELECTRODE  
 (E.G., GRID) INTERPOSED BETWEEN TWO ELECTRODES  
 313/304 .Plural-parallel-section cathode with electrode  
 surrounding each section

2 313/310 (1 OR, 1 XR)  
 Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
 313/310 DISCHARGE DEVICES HAVING A THERMIONIC OR  
 EMISSIVE CATHODE

2 313/361.1 (0 OR, 2 XR)  
 Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
 313/359.1 WITH POSITIVE OR NEGATIVE ION ACCELERATION  
 313/361.1 .Means for deflecting or focusing

2 313/414 (0 OR, 2 XR)  
 Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
 313/364 CATHODE RAY TUBE

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313/409 .Plural beam generating or control  
313/414 ..With focusing and accelerating electrodes

2 313/447 (0 OR, 2 XR)

Class 313 : ELECTRIC LAMP AND DISCHARGE DEVICES  
313/364 CATHODE RAY TUBE  
313/441 .Ray generating or control  
313/446 ..Including cathode assembly  
313/447 ...With control grid adjacent cathode

2 315/106 (0 OR, 2 XR)

Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
  
315/94 WITH CATHODE OR CATHODE HEATER SUPPLY CIRCUIT  
  
315/105 .Pulsating or A.C. supply to the cathode or  
heater circuit  
315/106 ..Automatic cut-out or voltage regulator in th

e

cathode or heater circuit

2 315/111.21 (1 OR, 1 XR)

Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
  
315/111.01 DISCHARGE DEVICE LOAD WITH FLUENT MATERIAL  
SUPPLY TO THE DISCHARGE SPACE  
315/111.21 .Plasma generating

2 315/291 (0 OR, 2 XR)

Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
  
315/291 CURRENT AND/OR VOLTAGE REGULATION

2 315/3.5 (1 OR, 1 XR)

Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
  
315/1 CATHODE RAY TUBE CIRCUITS  
315/3 .Combined cathode ray tube and circuit element  
structure  
315/3.5 ..Traveling wave tube with delay-type  
transmission line

2 315/307 (2 OR, 0 XR)

Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS  
  
315/291 CURRENT AND/OR VOLTAGE REGULATION  
315/307 .Automatic regulation

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2 315/5.37 (2 OR, 0 XR)  
 Class 315 : ELECTRIC LAMP AND DISCHARGE DEVICES: SYSTEMS

315/1 CATHODE RAY TUBE CIRCUITS  
 315/3 .Combined cathode ray tube and circuit element  
 structure  
 315/4 ..Inductor or distributed parameter-type  
 inductive structure  
 315/5 ...Ray passes in or through a hollow  
 distributed parameter device  
 315/5.37 ....Device has particular grid structure

2 378/113 (1 OR, 1 XR)  
 Class 378 : X-RAY OR GAMMA RAY SYSTEMS OR DEVICES

378/91 ELECTRONIC CIRCUIT  
 378/101 .X-ray source power supply  
 378/113 ..Electron beam control